



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : YEH
Application No. : 10/601,701
Filed : June 24, 2003
Title : METHOD FOR FABRICATION OF
POLYCRYSTALLINE SILICON THIN
FILM TRANSISTORS
Group Art Unit : 2812
Examiner : S. Isaac
Docket No. : 3230-56

MAIL STOP AMENDMENT

Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action of May 25, 2005, the period for response to which has been extended to expire on **October 25, 2005** by the filing herewith of a Petition for a two-month extension of time and payment of the required fee, please amend the above-identified application as follows: